Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

Claim 1 (Currently amended): A probe card structure comprising:

a probe section sections comprising having an insulated circuit board, a probe probes of silicon material which are being formed on the said insulated circuit board, and are in contact for contacting with the a pad of a device to be measured, and a conductive wiring electrically connected in electrical communication with to the said probe probes and formed disposed on the said insulated circuit board;

<u>a</u> supporting <u>structure</u> <u>structures which for</u> <u>supporting</u> <u>support each of the said</u> probe <u>section</u> <u>sections</u>;

 \underline{a} fixing structure which for fixes fixing the \underline{a} plurality of said supporting structures together;

 \underline{a} printed circuit which is having a conductive wiring connected to the said fixing structure, said

<u>printed circuit and is being</u> electrically connected to the <u>a</u> measurement device <u>for</u> transmitting the <u>a</u> measurement <u>signal</u> signals to the <u>said</u> device to be being measured, and has conductive wiring; and

<u>a</u> wiring connection means for electrically connecting the <u>said conductive</u> wiring of the <u>said probe</u> probes and the <u>said conductive</u> wiring <u>in communication</u> with of the <u>said</u> printed circuit.

Claim 2 (Currently amending): The probe card structure according to of claim 1 Claim 1, wherein the said supporting structures structure and the said fixing structure are made of one a material selected from the group consisting of invar, kovar, quartz, and ceramic, and any combinations thereof.

Claim 3 (Currently amended): The probe card structure according to Claim 1 of claim 1, wherein the said conductive wiring of the said probe section and the said conductive wiring of the said printed circuit are electrically connected by a sub-printed circuit, said sub-printed circuit being selected from the group consisting of which can be a flexible printed circuit, a of rigid printed circuit board, and any combinations thereof.

Claim 4 (Currently amended): The probe card structure according to of Claim 3, claim 3, wherein the said conductive wiring of the said probe section and the a conductive wiring of the said sub printed circuit are electrically connected by a metallic wire, said metallic wire being formed by the a wire bonding method.

Claim 5 (Currently amended): The probe card structure according to Claim 3, of claim 3, wherein the said conductive wiring of the said probe section and the a conductive wiring of the a flexible circuit are electrically connected by the an anisotropic conducting film.

Claim 6 (Currently amended): The probe card structure according to Claim 3, of claim 3, wherein further comprising at least one capacitor is installed to reduce the an electric noise on the a flexible printed circuit.

Claim 7 (Currently amended): The probe card structure according to Claim 3, of claim 3, wherein further comprising a contact pad of the said sub printed circuit and the a contact pad of the said insulated circuit board are electrically connected by a pogo pin.

Claim 8 (Currently amended): The probe card structure according to Claim 3[[,]] of claim 3, wherein further comprising the a contact pad of the said sub printed circuit and the a contact pad of the said insulated circuit board are electrically connected by an perpendicular conductor of silicon rubber material which conducts for conducting electricity between a top and a bottom surface through a plurality of vertically embedded metallic wires with having a diameter of 35µm or less, said plurality of vertically embedded metallic wires being positioned in an array of a 0.07 [[~]] through 0.45mm matrix.

Claim 9 (Currently amended): The probe card structure according to Claim 3, of claim 3, wherein further comprising a plating layer is formed on the said probe of the said probe section and the said conductive wiring of said probe section.

Claim 10 (Currently amended): The probe card structure according to Claim 9, of claim 9, wherein the said plating layer is formed by selected from the group consisting of a nickel plating layer, Θ a gold plating layer, and any combinations thereof.

Claim 11 (Currently amended): The probe card structure according to Claim 10, of claim 10, wherein further comprising a groove is formed at the a tip of

the <u>said probe</u> probes before the <u>said</u> plating layer is formed.

Claim 12 (Currently amended): The probe card structure according to Claim 1, of claim 1, wherein further comprising at least a screw is installed in the said supporting structure to for adjust adjusting the 3-dimensional a locations location of the said supporting structures structure and the said fixing structures structure, said location being adjustable in three dimensions.

Claim 13 (Currently amended): The probe card structure according to Claim 1, of claim 1, wherein further comprising at least a screw is installed in the said fixing structure, said screw to for adjusting adjust the 3-dimensional a location locations of the said supporting structures structure and the said fixing structures structure, said location being adjustable in three dimensions.